

Membership Publications/Services Standards Conferences Careers/Jobs

IEEE Xplore

Help FAQ Terms IEEE Peer Review **Quick Links**

» Adva

Welcome to IEEE Xplore

- Home
- What Can I Access?
- Log-out

CONTENTS

- Journals & Magazines
- Conference Proceedings
- Standards

SEARCH

- By Author
- Basic
- Advanced

MEMBER SERVICES

- Join IEEE
- Establish IEEE Web Account
- Access the IEEE Member Digital Library

- Access the IEEE Enterprise File Cabinet

Try our New Full-text Search Prototype 

Help

- 1) Enter a single keyword, phrase, or Boolean expression.
Example: acoustic imaging (means the phrase acoustic imaging plus any stem variations)
- 2) Limit your search by using search operators and field codes, if desired.
Example: optical <and> (fiber <or> fibre) <in> ti
- 3) Limit the results by selecting Search Options.
- 4) Click Search. See [Search Examples](#)

```
(calibration<or>calibrated<or>
calibrate<or>calibrating)
<paragraph>wafer<and>
(align<or>aligning<or>alignmen
```

Start Search **Clear**

Note: This function returns plural and suffixed forms of the keyword(s).

Search operators: <and> <or> <not> <in> [More](#)

Field codes: au (author), ti (title), ab (abstract), jn (publication name), de (index term) [More](#)

Search Options:

Select publication types:

- IEEE Journals
- IEE Journals
- IEEE Conference proceedings
- IEE Conference proceedings
- IEEE Standards

Select years to search:

From year: **All**  to **Present** 

Organize search results by:

Sort by: **Relevance** 
In: **Descending**  order
List **15**  Results per page

[IEEE Home](#) | [Search IEEE](#) | [Shop](#) | [Web Account](#) | [CONTACT IEEE](#)

[Membership](#) [Publications](#) [Services](#) [Standards](#) [Conferences](#) [Careers/Jobs](#)

[Help](#) [FAQ](#) [Terms](#) [IEEE Peer Review](#) [Quick Links](#)

IEEE Voice

Welcome United States Patent and Trademark Office

[Search Results](#)

Home What Can I Access? Log-out

Refine This Search:

Your search matched **7** of **1047691** documents.
A maximum of **500** results are displayed, **15** to a page, sorted by **Relevance** in **Descending** order.

Refine This Search: You may refine your search by editing the current search expression or entering a new one in the text box.
 Check to search within this result set

Results Key:

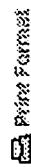
JNL = Journal or Magazine **CNF** = Conference **STD** = Standard

By Author Basic Advanced

1 Precise beam incidence angle control on the VIISta 810HP
Weeman, J.; Olson, J.; Guo, B.N.; Jeong, U.; Li, G.C.; Mehta, S.;
Ion Implantation Technology. 2002. Proceedings of the 14th International Conference on, 22-27 Sept. 2002
Pages:276 - 278
[Abstract] [\[PDF Full-Text \(335 KB\)\]](#) [IEEE CNF](#)

2 DC-SQUIDS fabricated by electron beam direct writing
Carelli, P.; Foglietti, V.; Leoni, R.;
Magnetics, IEEE Transactions on, Volume: 23 , Issue: 2 , Mar 1987
Pages:1087 - 1089
[Abstract] [\[PDF Full-Text \(560 KB\)\]](#) [IEEE JNL](#)

Access the IEEE Member Digital Library Access the IEEE Enterprise File Cabinet



3 100 GHz wafer probes based on photoconductive sampling
Feuer, M.D.; Shunk, S.C.; Smith, P.R.; Nuss, M.C.; Law, N.H.;
Photronics Technology Letters, IEEE , Volume: 5 , Issue: 3 , March 1993
Pages:361 - 364

[Abstract] [\[PDF Full-Text \(356 KB\)\]](#) [IEEE JNL](#)

4 Production use of an integrated automatic defect classification (ADC) system operating in a laser confocal/white light imaging defect review station
Li, J.; McIntyre, M.; Lee, K.; Worster, B.;
Advanced Semiconductor Manufacturing Conference and Workshop, 1996. ASMC
96 Proceedings. IEEE/SEMI 1996 , 12-14 Nov. 1996
Pages:107 - 111

[Abstract] [\[PDF Full-Text \(452 KB\)\]](#) [IEEE CNF](#)

5 A (100) silicon stress test chip with optimized piezoresistive sensor rosettes
Jaeger, R.C.; Suhling, J.C.; Anderson, A.A.;
Electronic Components and Technology Conference, 1994. Proceedings., 44th , 1-4
May 1994
Pages:741 - 749

[Abstract] [\[PDF Full-Text \(664 KB\)\]](#) [IEEE CNF](#)

6 Broadband optoelectronic wafer probing
Feuer, M.D.; Shunk, S.C.; Smith, P.R.; Law, H.H.; Burrus, C.A.; Nuss, M.C.;
High Speed Semiconductor Devices and Circuits, 1993. Proceedings., IEEE/Cornell
Conference on Advanced Concepts in , 2-4 Aug. 1993
Pages:485 - 493

[Abstract] [\[PDF Full-Text \(556 KB\)\]](#) [IEEE CNF](#)

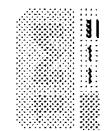
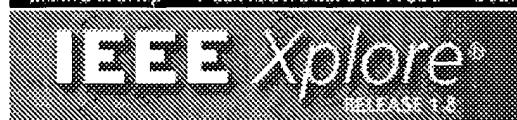
7 Emissivity correcting pyrometer for temperature measurement in low pressure chemical vapor deposition
Fordham, M.J.; Gansman, R.F.; Sorrell, F.Y.;
University/Government/Industry Microelectronics Symposium, 1993., Proceedings
of the Tenth Biennial , 18-19 May 1993

Pages:223 - 228

[\[Abstract\]](#) [\[PDF Full-Text \(424 KB\)\]](#) [\[IEEE CNF\]](#)

[Home](#) | [Log-out](#) | [Journals](#) | [Conference Proceedings](#) | [Standards](#) | [Search by Author](#) | [Basic Search](#) | [Advanced Search](#) | [Join IEEE](#) | [Web Account](#) | [New this week](#) | [OPAC](#) | [Linking Information](#) | [Your Feedback](#) | [Technical Support](#) | [Email Alerting](#) | [No Robots, Please](#) | [Release Notes](#) | [IEEE Online Publications](#) | [Help](#) | [FAQ](#) | [Terms](#) | [Back to Top](#)

Copyright © 2004 IEEE — All rights reserved



- Home
- What Can I Access?
- Log-out

- Journals & Magazines
- Conference Proceedings
- Standards

- By Author
- Basic
- Advanced

- Join IEEE
- Establish IEEE Web Account
- Access the IEEE Member Digital Library

- Access the IEEE Enterprise File Cabinet

Try our New Full-text Search Prototype 

Help

- 1) Enter a single keyword, phrase, or Boolean expression.
Example: acoustic imaging (means the phrase acoustic imaging plus any stem variations)
- 2) Limit your search by using search operators and field codes, if desired.
Example: optical <and> (fiber <or> fibre) <in> ti
- 3) Limit the results by selecting Search Options.
- 4) Click Search. See [Search Examples](#)

```
(calibration<or>calibrated<or>
calibrate<or>calibrating)
<paragraph>wafer<and>
(pattern<or>patterns<or>crucif
```

Note: This function returns plural and suffixed forms of the keyword(s).

Search operators: <and> <or> <not> <in> [More](#)

Field codes: au (author), ti (title), ab (abstract), jn (publication name), de (index term) [More](#)

Search Options:**Select publication types:**

- IEEE Journals
- IEE Journals
- IEEE Conference proceedings
- IEE Conference proceedings
- IEEE Standards

Select years to search:

From year: to

Organize search results by:

Sort by:
 In: order
 List Results per page



Pages:867 - 872

[Abstract] [PDF Full-Text (152 KB)] IEEE JNL

3 Real-time estimation of patterned wafer parameters using in situ spectroscopic ellipsometry*Galazza, C.G.; Khargonekar, P.P.; Terry, F.L., Jr.;*

Control Applications, 1999. Proceedings of the 1999 IEEE International Conference on , Volume: 1 , 22-27 Aug. 1999

Pages:773 - 778 vol. 1

[Abstract] [PDF Full-Text (480 KB)] IEEE CNF

4 How good is your calibration? A post-mortem examination and recalibration*Aguilera, J.; Fisher, B.;*

Instrumentation and Measurement Technology Conference, 1990. IMTC-90. Conference Record., 7th IEEE , 13-15 Feb. 1990

Pages:195

[Abstract] [PDF Full-Text (28 KB)] IEEE CNF

5 Hybrid optical-electrical overlay test structure [for CMOS]*Cresswell, M.W.; Allen, R.A.; Linholm, L.W.; Guthrie, W.F.; Gurnell, A.W.;*

Microelectronic Test Structures, 1996. ICMTS 1996. Proceedings. 1996 IEEE International Conference on , 25-28 March 1996

Pages:9 - 16

[Abstract] [PDF Full-Text (380 KB)] IEEE CNF

6 Analysis of the impact of proximity correction algorithms on circuit performance*Li Chen; Milor, L.S.; Ouyang, C.H.; Maly, W.; Yeng-Kaung Peng;*

Semiconductor Manufacturing, IEEE Transactions on , Volume: 12 , Issue: 3 , Aug. 1999

Pages:313 - 322

[Abstract] [PDF Full-Text (284 KB)] IEEE JNL

7 **A three-step method for the de-embedding of high-frequency S-parameter measurements**

Cho, H.; Burk, D.E.;

Electron Devices, IEEE Transactions on , Volume: 38 , Issue: 6 , June 1991

Pages:1371 - 1375

[Abstract] [\[PDF Full-Text \(444 KB\)\]](#) [\[IEEE JNL\]](#)

8 **Production use of an integrated automatic defect classification (ADC) system operating in a laser confocal/white light imaging defect review station**

Li, J.; McIntyre, M.; Lee, K.; Worster, B.;

Advanced Semiconductor Manufacturing Conference and Workshop, 1996. ASMC 96 Proceedings. IEEE/SEMI 1996 , 12-14 Nov. 1996

Pages:107 - 111

[Abstract] [\[PDF Full-Text \(452 KB\)\]](#) [\[IEEE CNF\]](#)

9 **Removal of cable and connector dispersion in time-domain waveform**

measurements on 40 Gb integrated circuits

Scott, J.; Behnia, B.; Bossche, M.V.; Cognata, A.; Verspecht, J.; Verbeyst, F.;

Thorn, M.; Scherr, D.R.;

Microwave Symposium Digest, 2002 IEEE MTT-S International , Volume: 3 , 2-7 June 2002

Pages:1669 - 1672

[Abstract] [\[PDF Full-Text \(487 KB\)\]](#) [\[IEEE CNF\]](#)

10 **An on-wafer fabricated free-chlorine sensor**

van den Berg, A.; Koudelka-Hep, M.; van der Schoot, B.K.; Verney-Norberg, E.;

Krebs, P.; Grisel, A.; de Rooij, N.F.;

Solid-State Sensors and Actuators, 1991. Digest of Technical Papers, TRANSDUCERS '91, 1991 International Conference on , 24-27 June 1991

Pages:233 - 236

[Abstract] [\[PDF Full-Text \(448 KB\)\]](#) [\[IEEE CNF\]](#)

11 **Junction-isolated electrical test structures for critical dimension calibration standards**

Allen, R.A.; Cresswell, M.W.; Linholm, L.W.; Semiconductor Manufacturing, IEEE Transactions on , Volume: 17 , Issue: 2 , May 2004
Pages:79 - 83

[Abstract] [\[PDF Full-Text \(208 KB\)\]](#) [\[IEEE JNL\]](#)

12 DC-SQUIDS fabricated by electron beam direct writing

Carelli, P.; Foglietti, V.; Leoni, R.,

Magnetics, IEEE Transactions on , Volume: 23 , Issue: 2 , Mar 1987

Pages:1087 - 1089

[Abstract] [\[PDF Full-Text \(560 KB\)\]](#) [\[IEEE JNL\]](#)

13 Enhanced on-wafer time-domain waveform measurement through removal of interconnect dispersion and measurement instrument jitter

Scott, J.B.; Verspecht, J.; Behnia, B.; Vanden Bossche, M.; Cognata, A.; Verbeyst, F.; Thorn, M.L.; Scherrer, D.R.,

Microwave Theory and Techniques, IEEE Transactions on , Volume: 50 , Issue: 12 , Dec. 2002

Pages:3022 - 3028

[Abstract] [\[PDF Full-Text \(581 KB\)\]](#) [\[IEEE JNL\]](#)

14 A microneedle-based glucose monitor: fabricated on a wafer-level using in-device enzyme immobilization

Zimmermann, S.; Fienbork, D.; Stoeber, B.; Flounders, A.W.; Liepmann, D.,

TRANSDUCERS, Solid-State Sensors, Actuators and Microsystems, 12th International Conference on, 2003 , Volume: 1 , 8-12 June 2003

Pages:99 - 102 vol.1

[Abstract] [\[PDF Full-Text \(402 KB\)\]](#) [\[IEEE CNF\]](#)

15 Automated metrology qualification strategy [IC measurement]

Chain, E.E.,

Advanced Semiconductor Manufacturing Conference and Workshop, 1996. ASMC

96 Proceedings. IEEE/SEMI 1996 , 12-14 Nov. 1996

Pages:337 - 342

[\[Abstract\]](#) [\[PDF Full-Text \(712 KB\)\]](#) [IEEE CNF](#)

[1](#) [2](#) [Next](#)

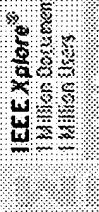
[Home](#) | [Log-out](#) | [Journals](#) | [Conference Proceedings](#) | [Standards](#) | [Search by Author](#) | [Basic Search](#) | [Advanced Search](#) | [Join IEEE](#) | [Web Account](#) | [New this week](#) | [OPAC Linking Information](#) | [Your Feedback](#) | [Technical Support](#) | [Email Alerting](#) | [No Robots Please](#) | [Release Notes](#) | [IEEE Online Publications](#) | [Help](#) | [FAQ](#) | [Terms](#) | [Back to Top](#)

Copyright © 2004 IEEE — All rights reserved



IEEE

[Search IEEE](#) | [Shop](#) | [Web Account](#) | [Contact IEEE](#)



IEEE Xplore®
Digital Documents
Collection

[Search Results](#)

IEEE Xplore®

Welcome
United States Patent and Trademark Office

[Quick Links](#)

Your search matched **18** of **1047691** documents.
A maximum of **500** results are displayed, **15** to a page, sorted by **Relevance** in **Descending** order.

[Refine This Search](#)

You may refine your search by editing the current search expression or entering a new one in the text box.

[Search](#)

Check to search within this result set

Results Key:

JNL = Journal or Magazine **CNF** = Conference **STD** = Standard

16 Measurement of the linewidth of electrical test-structure reference features by automated phase-contrast image analysis

am Ende, B.A.; Cresswell, M.W.; Allen, R.A.; Headley, T.J.; Guthrie, W.F.; Linholm, L.W.; Bogardus, E.H.; Murabito, C.E.;

Microelectronic Test Structures, 2002. ICMTS 2002. Proceedings of the 2002 International Conference on , 8-11 April 2002

Pages:1 - 6

[\[Abstract\]](#) [\[PDF Full-Text \(391 KB\)\]](#) [IEEE CNF](#)

17 Calibration technique for MEMS membrane type strain sensors

Li Cao; Tae Song Kim; Jia Zhou; Mantell, S.C.; Polla, D.L.;

University/Government/Industry Microelectronics Symposium, 1999. Proceedings of the Thirteenth Biennial , 20-23 June 1999

Pages:204 - 210

[Access the IEEE Member Digital Library](#)

[Print Format](#)[\[Abstract\]](#) [\[PDF Full-Text \(356 KB\)\]](#) [IEEE CNF](#)**18 Thermolectric microsensor for heat flux measurement**

Volk/ein, F.; Kessler, E.;
Thermoelectrics, 1998. Proceedings ICT 98. XVII International Conference on , May
24-28, 1998
Pages:214 - 217

[\[Abstract\]](#) [\[PDF Full-Text \(280 KB\)\]](#) [IEEE CNF](#)[Prev](#) [1](#) [2](#)